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JPM

Attorney Docket SEL 191

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of)
)
Tanaka et al.)
)
Serial No.: 09/610,637)
)
Filed: July 5, 2000)
)
For: Laser Irradiation Apparatus, Laser)
Irradiation Method, Semiconductor)
Device And Method Of Manufacturing)
A Semiconductor Device)

Art Unit: 2813)
)
)
)

Examiner: David S. Blum)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT C (AFTER FINAL)

Sir:

In response to the Final Rejection of October 13, 2004, a one month extension of time being submitted herewith, please enter the following amendment in the above-identified application:

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:
Commissioner for Patents ,
P.O. Box 1450, Alexandria, VA 22313-1450 on

February 11 2005

(Date of Deposit)

Shannon Wallace

Name of applicant, assignee, or Registered Rep.

Shannon Wallace 2/11/05

Signature

Date

BEST AVAILABLE COPY

Okay
To GWR
2/1/05